Search Notes

| Application/Control No. | Applicant(s)/Patent under Reexamination | |
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| 10/815,619 | 4100 | |
| Examiner | Art Unit | |
| Tae W. Kim | 2876 | |

| SEARCHED | | | | | | | |
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| Class | Subclass | Date | Examiner | | | | |
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| INTERFERENCE SEARCHED | | | | | | |
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| (INCLUDING SEARCH STRATEGY) DATE EXMF | | | |
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| | DATE | EXMR | |
| Test Search | 4/25/2006 | KIM | |
| East | 4/25/2006 | KIM | |
| Partial Class Search: 235/383, 235/431, 235/462.01, 705/016, 714/781 | 4/25/2006 | KIM | |
| Partial search history lost due to technical issues | 4/24/2006 | KIM | |
| Consulted with Jared Fureman @ AU 2876 | 8/3/2006 | KIM | |
| Search Updated | 8/3/2006 | КІМ | |
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